

ECE 4244/ENGR 4244: Nanotechnology II

Credits and contact hours: 3 Credits (One 60-minute lecture and one 3-hour lab per week)

Instructor: Faquir Jain

Textbook: Nanotechnology Laboratory-II.
F. Jain (2018)

- a. *Other supplemental materials:* Selected reference materials/articles distributed in class and posted on line.

Specific course information:

- a. **Catalog Description:** Growth and characterization of carbon nanotubes using vapor phase nucleation; growth of CdSe quantum dots using liquid phase precipitation and vapor phase MOCVD reactor; characterization using AFM and TEM and dynamic scattering techniques; device processing highlighting nanolithography (E-Beam), and self-assembly techniques; project work involving fabrication of devices such as LEDs, carbon nanotube based FETs, and biosensors using self-assembled quantum dots hosted in inorganic or organic/polymer layers.
- b. *Prerequisite:* ECE 4211 or ECE/ENGR 4243.
- c. *Required, elective, or selected elective:* Selected elective (EE)

Specific goals for the course:

- a. *Specific outcomes of instruction:* Students will be able to
 - Carry out the processing of nanoelectronic device fabrication and characterization and compare theoretical models and experimental data.
 - Perform wafer characterization using four-point probe, Hall Effect, thermoelectric probe, and crystal orientation; perform characterization of quantum dots using AFM, TEM, Raman spectroscopy, Dynamic light scattering.
 - Perform Quantum well/dot characterization using Photoluminescence and X-ray diffraction.
 - Fabricate discrete devices such as quantum dot diodes and solar cells, Quantum dot gate (QDG) FETs and nonvolatile memories, QDG protein sensors; analyze I-V, C-V characteristics using Parametric Analyzer and other instrumentation. Measure oxide thickness, junction depth and compare with theoretical models.
 - Select and design devices and simple integrated circuits.
 - Communicate via oral presentation and written report the project including processing steps, device/circuit performance and compare with analytical models.
 - Search for, acquire and use new knowledge from multiple sources.
- b. *ABET Criterion 3 Student Outcomes addressed by the course:*

- (1) **an ability to identify, formulate, and solve complex engineering problems by applying principles of engineering, science, and mathematics**
Students learn to analyze fabricated semiconductor devices by applying techniques from mathematics, science and engineering.
- (2) **an ability to apply engineering design to produce solutions that meet specified needs with consideration of public health, safety, and welfare, as well as global, cultural, social, environmental, and economic factors**
Students formulate and implement design to provided specifications.
- (3) **an ability to communicate effectively with a range of audiences**
Students write pre and post lab technical report; also present the results of their project to the class.
- (4) **an ability to recognize ethical and professional responsibilities in engineering situations and make informed judgments, which must consider the impact of engineering solutions in global, economic, environmental, and societal contexts**
n/a
- (5) **an ability to function effectively on a team whose members together provide leadership, create a collaborative and inclusive environment, establish goals, plan tasks, and meet objectives**
n/a
- (6) **an ability to develop and conduct appropriate experimentation, analyze and interpret data, and use engineering judgment to draw conclusions**
n/a
- (7) **an ability to acquire and apply new knowledge as needed, using appropriate learning strategies.**
Students use the web, library databases, and other resources for their technical reports.

Topics covered:

- Semiconductor wafer characterization: Measurements of mobility, resistivity, doping type, crystal orientation; learn characterization of quantum dots using AFM, TEM, Raman spectroscopy, Dynamic light scattering.
- Diffusion of p- and n-type dopants in Si to form unction diodes and solar cells; dry and wet oxidation of Si to fabricated MOS capacitors and FETs,
- Fabricate discrete devices such as quantum dot diodes and solar cells, Quantum dot gate (QDG) FETs and nonvolatile memories, QDG protein sensors; analyze I-V, C-V characteristics using Parametric Analyzer and other instrumentation. Measure oxide thickness, junction depth and compare with theoretical models.
- Project work include fabrication of inverters using FETs, nonvolatile memories, SRAMs and biosensors.